

# Electron Beam Lithography Central Facility (Zeiss Sigma 300 + NPGS v9)

Booking request form for external users ( not from IIT Bombay)

1	Name	
2	Institution	
		Please select (tick) one
3	A. Academic Institute (Indian)	
	B. National Lab (Indian)	
	C. Industry (Indian)	
	D. Start up (SINE)	
	E. Monash-IITB	
	F. SAARC / African Academic institute	
	G. SAARC / African Industry	
	H. Other country : Academic institute	
	I. Other country : Industry	
4	Substrate material of your sample (e.g. Si/SiO <sub>2</sub> , GaAs, Sapphire etc..)	
5	Approximate size of the sample (max size 2 cm x 2 cm)	
6	Electron Beam Resist type (e.g. PMMA, HSQ...)	
7	Have you compiled the pattern with QCAD in your local PC/laptop ? [Please consult the facility about how to prepare the CAD file prior to booking]	
8	Time required (1 slot = 3 hours)	
9	Confirm that the sample is free of any material that will outgass in vacuum (e.g. biological material, uncured resist etc)	